

Title (en)

Device and method for coating a even substrate

Title (de)

Vorrichtung und Verfahren zum Beschichten eines ebenen Substrates

Title (fr)

Dispositif et procédé de revêtement d'un substrat plan

Publication

**EP 1010473 B1 20060712 (DE)**

Application

**EP 99811153 A 19991213**

Priority

CH 249698 A 19981217

Abstract (en)

[origin: EP1010473A2] The arrangement has a coating module (2) with a capillary column filled with a liquid coating medium and with an opening past which the surface to be coated is moved at a relatively small distance so that a coating is deposited onto the surface. The capillary column is open at the bottom and is filled with coating medium via a supply chamber (25,27). The substrate (23) is passed beneath the opening of the column with the surface (23a) to be coated facing upwards. An Independent claim is also included for a method of coating a flat substrate.

IPC 8 full level

**B05C 5/02** (2006.01); **B05C 9/02** (2006.01); **B05C 11/10** (2006.01)

CPC (source: EP US)

**B05C 5/0254** (2013.01 - EP US); **B05C 9/02** (2013.01 - EP US); **B05C 11/1013** (2013.01 - EP US); **Y10S 118/04** (2013.01 - EP US)

Designated contracting state (EPC)

DE ES FR GB IT

DOCDB simple family (publication)

**EP 1010473 A2 20000621**; **EP 1010473 A3 20030528**; **EP 1010473 B1 20060712**; CA 2292271 A1 20000617; CA 2292271 C 20080318; DE 59913661 D1 20060824; ES 2274611 T3 20070516; MX PA99011776 A 20050419; US 6383571 B1 20020507

DOCDB simple family (application)

**EP 99811153 A 19991213**; CA 2292271 A 19991216; DE 59913661 T 19991213; ES 99811153 T 19991213; MX 9911776 A 19991215; US 46658499 A 19991217